

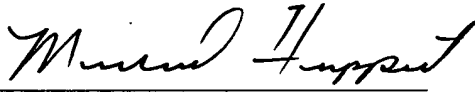
REMARKS

The present Preliminary Amendment is submitted to replace the title used in the International Application, cancel original claims 1-12 and add new claims 13-24.

Also, the abstract has been amended in order to remove the reference numerals therein. The changes to the abstract are submitted in the form of a substitute abstract. A copy of the abstract with changes marked therein is attached.

Respectfully submitted,

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ABSTRACT

A suction-and-holding face ~~(14)~~ for a component ~~(1)~~ in a suction nozzle ~~(3)~~ is formed from a semiconductor ceramic so that the suction-and-holding face to be brought into direct contact with the component in suction and holding has characteristics as semiconductor. Thus, detrimental effects due to occurrence of static electricity on the suction nozzle as well as detrimental effects due to an electrical conduction state between the suction nozzle and the component can be prevented from occurring.